

Machine Name : Field emission electron microscope

Brand : ZEISS

Machine Model : Sigma 300

Stock No. : 489738

Ex-factory Date : 2013



Main Technical Parameters:

Type of electron source: Schottky thermal field emission

Acceleration voltage: 100 V - 30 kV

Magnification: 12 $\times$ - 1,000,000 $\times$

SEM resolution:

1 nm @ 30 kV

1.5 nm @ 15 kV

2.8 nm @ 1 kV

Electron beam exposure size: 20 nm

Field stitching accuracy: <100 nm

Scanning frequency: 6 MHz

Graphic format: GDSII



